

L11	10	laser and semiconductor and dielectric and (crystallize) and (intensity adj distribution) and axis and exposure	USPAT	OR	ON	2005/04/19 15:31
L12	1	("6403396").PN.	USPAT	OR	OFF	2005/04/19 12:55
L13	2	laser and semiconductor and dielectric and (crystallize) and (intensity adj distribution) and axis and exposure and random	USPAT	OR	ON	2005/04/19 14:24
L14	2	laser and semiconductor and dielectric and (crystallize) and (intensity adj distribution) and axis and exposure and (single adj crystal) and grain	USPAT	OR	ON	2005/04/19 15:35
L15	1	laser and semiconductor and dielectric and (crystallize) and (intensity adj distribution) and axis and exposure and (single adj crystal) and grain and melt	USPAT	OR	ON	2005/04/19 15:54
L16	7	laser and semiconductor and dielectric and (crystallize) and (intensity adj distribution) and axis and (two with beams) and melt	USPAT	OR	ON	2005/04/19 16:02
L17	205	(219/121.65).CCLS.	USPAT	OR	OFF	2005/04/19 16:02
L18	636	(257/192).CCLS.	USPAT	OR	OFF	2005/04/19 16:02
L19	116	(438/150).CCLS.	USPAT	OR	OFF	2005/04/19 16:02
L20	3285	(430/270.1).CCLS.	USPAT	OR	OFF	2005/04/19 16:03
L21	690	(438/166).CCLS.	USPAT	OR	OFF	2005/04/19 16:03
L22	774	(438/149).CCLS.	USPAT	OR	OFF	2005/04/19 16:03
S1	1001	laser and semiconductor and dielectric and polycrystalline and intensity	USPAT	OR	OFF	2005/04/19 11:49
S2	24	laser and semiconductor and dielectric and polycrystalline and (intensity adj modulation)	USPAT	OR	OFF	2005/03/28 15:33
S3	0	laser and semiconductor and dielectric and polycrystalline and (intensity adj modulation) and (crystal adj grain)	USPAT	OR	OFF	2005/03/28 15:34
S4	5	laser and semiconductor and dielectric and polycrystalline and (intensity adj modulation) and (phase adj shift)	USPAT	OR	OFF	2005/04/11 15:40
S5	1	("6744065").PN.	USPAT	OR	OFF	2005/03/30 11:31
S6	1	laser and semiconductor and dielectric and polycrystalline and (intensity adj modulation) and (phase adj shift) and periodic	USPAT	OR	OFF	2005/04/11 15:40

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	47	laser and semiconductor and dielectric and polycrystalline and intensity and periodicity	USPAT	OR	OFF	2005/04/19 11:49
L2	2	laser and semiconductor and dielectric and polycrystalline and (intensity adj modulation) and periodicity	USPAT	OR	OFF	2005/04/19 12:41
L3	0	laser and semiconductor and dielectric and (crystallize with film) and (intensity adj modulation) and periodicity	USPAT	OR	OFF	2005/04/19 12:41
L4	0	laser and semiconductor and dielectric and (crystallize adj film) and (intensity adj modulation) and periodicity	USPAT	OR	OFF	2005/04/19 12:42
L5	1	laser and semiconductor and dielectric and (crystallize adj film) and (intensity adj modulation) and periodicity	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/04/19 12:42
L6	1	laser and semiconductor and dielectric and (polycrystall\$ with film) and (intensity adj modulation) and periodicity	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/04/19 12:43
L7	3	laser and semiconductor and dielectric and (polycrystall\$ with film) and (intensity adj modulation) and periodic\$	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/04/19 12:54
L8	10	laser and semiconductor and dielectric and (polycrystall\$ with film) and (intensity adj modulation) and axis and exposure	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/19 12:45
L9	55	laser and semiconductor and dielectric and (polycrystalline) and (intensity adj distribution) and axis and exposure	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/19 12:45
L10	29	laser and semiconductor and dielectric and (polycrystalline) and (intensity adj distribution) and axis and exposure	USPAT	OR	ON	2005/04/19 12:45

S7	86	laser and semiconductor and dielectric and polycrystalline and intensity and (excimer adj laser) and anneal\$ and axis and (crystal adj grain)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/12 13:48
S8	33241617	laser and semiconductor and dielectric and polycrystalline and intensity and (excimer adj laser) and anneal\$ and axis and (crystal adj grain) and (active adj matrix) and modulation and phase	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/12 13:48
S9	5	laser and semiconductor and dielectric and polycrystalline and intensity and (excimer adj laser) and anneal\$ and axis and (crystal adj grain) and (active adj matrix) and modulation and periodic	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/12 13:49